

What is claimed is:

1. A vacuum processing apparatus, comprising;
 - a cassette hold means for holding a first cassette storing substrates to be processed, in the atmosphere;
 - a cassette hold means for holding a second cassette storing dummy substrates, in the atmosphere;
 - a plurality of vacuum processing chambers, having a substrate table on which either one of said substrates or one of said dummy substrates is placed;
 - at least one transferring chamber, having an evacuating device, for transferring said substrates and said dummy substrates between the atmosphere and said vacuum processing chambers;
 - a conveyor for transferring said substrates and said dummy substrates, between (a) said first and second cassettes and (b) said vacuum processing chambers; and
 - a control means arranged to control said conveyor so as to transfer said substrates between said first cassette and said vacuum processing chambers, and said dummy substrates between said second cassette and said vacuum processing chamber,
 - wherein said control means is arranged to control said conveyor so that said substrates to be processed and said dummy substrates do not coexist inside the same chamber in vacuum.

2. A vacuum processing apparatus, comprising;
 - a cassette hold means for holding a first cassette storing substrates to be processed, in the atmosphere;
 - a cassette hold means for holding a second cassette storing dummy substrates, in the atmosphere;
 - a plurality of vacuum processing chambers, having a substrate table on which either one of said substrates or one of said dummy substrates is placed for processing one by one;
 - at least one transferring chamber, having an evacuating device, for transferring said substrates and said dummy substrates between the atmosphere and said vacuum processing chambers;
 - a conveyor for transferring said substrates and said dummy substrates, between (a) said first and second cassettes and (b) said vacuum processing chambers; and
 - a control means arranged to control said conveyor so as to transfer said substrates between said first cassette and said vacuum processing chambers, and said dummy substrates between said second cassette and said vacuum processing chambers,
 - wherein said control means is arranged to control said conveyor so that said substrates to be processed and said dummy substrates do not coexist inside the same chamber in vacuum.